

**AMENDMENTS TO THE CLAIMS**

**Please amend the claims as follows:**

1.-7. (Canceled)

8. (Previously Presented) A remote control system for one or more semiconductor manufacturing apparatuses comprising:

a local area network system comprising a plurality of host devices each connected with one or more semiconductor manufacturing apparatuses, and a router connected with said host devices; and

a remote operation device including a router that accesses said host devices by way of a communication line;

wherein said host devices are each provided with an IP routing function for achieving remote control operation from said remote operation device, and a communication element having a call incoming function of receiving a call incoming from said communication line, and

said host devices each perform user authentication when said remote operation device connects to said host devices, so that said remote operation device thus authenticated can individually simultaneously display a same screen as that displayed on each of said host devices, permitting said remote operation device to remotely control and operate said host devices,

wherein said remote operation device thus authenticated replaces operation parameter files of said host devices through remote control.

9. (Original) The remote control system for one or more semiconductor manufacturing apparatuses according to claim 8, wherein said communication line connecting between said host devices and said remote operation device comprises the Internet.

10. (Previously Presented) The remote control system for one or more semiconductor manufacturing apparatuses according to claim 8, wherein said communication line connecting between said host devices and said remote operation device comprises one of a local area network and a wide area network.

11. (Previously Presented) A remote control system for one or more semiconductor manufacturing apparatuses comprising:

a local area network system comprising a plurality of host devices each connected with at least one semiconductor manufacturing apparatuses, and an access server connected with said host devices; and

a plurality of remote operation devices each having a communication element accessible to said host devices by way of a communication network;

wherein said host devices are each provided with an IP routing function for achieving remote control operation from each of said remote operation devices, and

said host devices each perform user authentication when each of said remote operation devices connects to said host devices,

wherein each of said remote operation devices thus authenticated can individually simultaneously display a same screen as that displayed on each of said host devices, permitting said remote operation devices to remotely control and operate said host devices,

wherein each of said remote operation devices thus authenticated replaces operation parameter files of each of said host devices through remote control.

12. (Previously Presented) The remote control system for one or more semiconductor manufacturing apparatuses according to claim 11, wherein said communication network connecting between said host devices and said remote operation devices comprises at least one of a public telephone network, an ISDN network, the Internet, a local area network and a wide area network.

13. (Canceled)

14. (Previously Presented) The remote control system for one or more semiconductor manufacturing apparatuses according to claim 8, wherein said remote operation device enables same operations as those carried out by said host devices.

15. (Previously Presented) The remote control system for one or more semiconductor manufacturing apparatuses according to claim 11, wherein each of said remote operation

devices enables same operations as those carried out by said host devices.

16.-17. (Canceled)

18. (Previously Presented) The remote control system for one or more semiconductor manufacturing apparatuses according to claim 8, further comprising a display screen associated with the host device and a display screen associated with the remote operation device.

19. (Previously Presented) The remote control system for one or more semiconductor manufacturing apparatuses according to claim 11, further comprising a display screen associated with the host device and a display screen associated with the remote operation device.